



## Full Length Article

# Rational design of multifunctional devices based on molybdenum disulfide and graphene hybrid nanostructures



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## ABSTRACT

We rationally designed a new type of hybrid materials, molybdenum disulfide (MoS<sub>2</sub>) synthesized by Mo pre-deposition followed by subsequent sulfurization process directly on thermal chemical vapor deposition (TCVD)-grown graphene, for applications in a multifunctional device. The synthesis of stoichiometric and uniform multilayer MoS<sub>2</sub> and high-crystalline monolayer graphene was evaluated by X-ray photoelectron spectroscopy and Raman spectroscopy. To examine the electrical transport and photoelectrical properties of MoS<sub>2</sub>-graphene hybrid films, field effect transistors (FETs) and visible-light photodetectors based on MoS<sub>2</sub>-graphene were both fabricated. As a result, the extracted mobility for MoS<sub>2</sub>-graphene hybrid FETs was two times higher than that of MoS<sub>2</sub> FETs. In addition, the MoS<sub>2</sub>-graphene photodetectors revealed a significant photocurrent with abrupt switching behavior under periodic illumination.

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## 1. Introduction

Considerable efforts have been devoted on the synthesis of two-dimensional MoS<sub>2</sub> for multifaceted applications such as field effect transistors (FETs) and photodetectors [1–4]. Among these applications, there are two crucial requirements for practical applications in MoS<sub>2</sub>-based FETs. Thus far, MoS<sub>2</sub> thin films have been produced by various methods, including mechanical exfoliation, chemical exfoliation, and thermal chemical vapor deposition (TCVD) [5–7]. Unfortunately, these methods are limited to the formation of MoS<sub>2</sub> flakes. Thus, to meet the demands of the target applications, the synthesis of large-area and continuous MoS<sub>2</sub> layers with spatial homogeneity is a prerequisite for compatibility of top-down lithographic fabrication techniques and obtaining the same responses from all devices. For the synthesis of continuous MoS<sub>2</sub> layers, (i) thermal decomposition of ammonium thiomolybdate ((NH<sub>4</sub>)<sub>2</sub>MoS<sub>4</sub>) thin films formed by dipping and spin-coating methods and (ii) the direct deposition of MoS<sub>2</sub> thin films followed by subsequent the sulfurization of Mo films have been adopted [8–11]. Meanwhile, it is widely recognized that the improvements of the carrier mobility in MoS<sub>2</sub> FETs and the photocurrent in MoS<sub>2</sub>

photodetectors are key issues for applications in next generation flexible nanoelectronics. In previous reports, the carrier mobility enhancement of MoS<sub>2</sub> FETs was demonstrated by adopting ionic-liquid gating, scandium electrodes, and a polymethyl methacrylate (PMMA) passivation layer [12–14]. On the other hand, the enhancement of photocurrent in MoS<sub>2</sub> phototransistors was achieved by depositing periodic Au nanoarrays induced by the local plasmonic enhancement effect [15] and transferring graphene with the high carrier mobility [16].

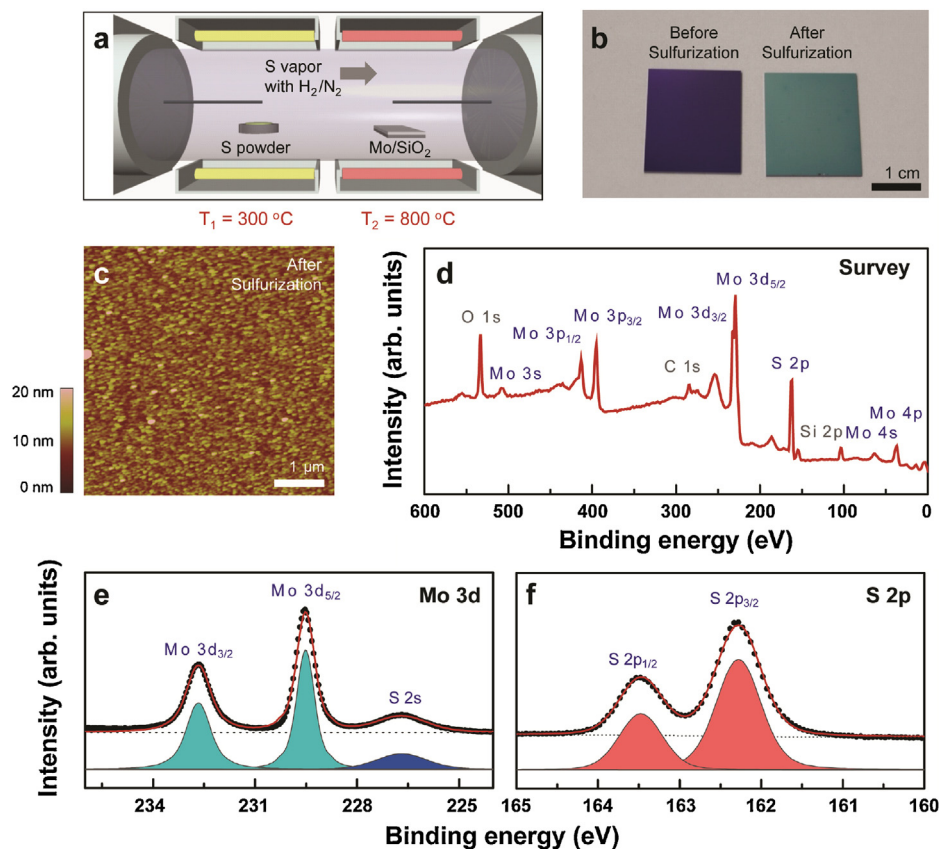
Herein, we present that the pre-deposition of Mo thin films and subsequent sulfurization were used for the synthesis large-area and continuous MoS<sub>2</sub> thin films. Moreover, we fabricated MoS<sub>2</sub>-graphene hybrid films-based FETs and photodetectors to combine advantages of MoS<sub>2</sub> and graphene.

## 2. Experimental details

The fabrication of MoS<sub>2</sub>-graphene hybrid films was implemented as follows: firstly, the synthesis of graphene was carried out on 25 μm-thick Cu foils using TCVD. The Cu foils were located in the TCVD chamber and annealed at 1000 °C for 3 min with introducing CH<sub>4</sub> (4 sccm), and H<sub>2</sub> (200 sccm) under a pressure of ~3 Torr to synthesize graphene. The synthesized graphene was transferred onto SiO<sub>2</sub> (300 nm)/Si(001) substrates by a poly(methyl methacrylate) (PMMA)-assisted wet transfer process [17]. Secondly, MoS<sub>2</sub> was

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**Fig. 1.** (a) A schematic illustration of a two-temperature-zone tube furnace setup for the synthesis of MoS<sub>2</sub> layers. (b) A photograph of the Mo thin film (left) before and (right) after sulfurization. (c) An AFM image of synthesized MoS<sub>2</sub> on SiO<sub>2</sub>/Si substrates. (d) The XPS survey, Mo 3d, and S 2p core level spectra of synthesized MoS<sub>2</sub>.

synthesized by a two-temperature-zone tube furnace, as depicted in Fig. 1a. 2 nm-thick Mo thin films were deposited onto the graphene/SiO<sub>2</sub>/Si substrates by DC magnetron sputtering. The Mo films and 0.01 g of S powder were located in the furnace, in which the distance between the Mo film and the S powder was 15 cm. The two zones for Mo films and S powder in the furnace were annealed at 300 and 800 °C, respectively, under a gas mixture of H<sub>2</sub>/N<sub>2</sub> (30 sccm) for 1 min with a pressure of 1 Torr for the synthesis of MoS<sub>2</sub>-graphene hybrid films.

### 3. Results and discussion

The morphological and chemical characterization of MoS<sub>2</sub> layers synthesized using the pre-deposition of Mo thin films and subsequent sulfurization process were carried out by atomic force microscopy (AFM) and X-ray photoelectron spectroscopy (XPS). Fig. 1b shows a photograph of Mo thin films deposited on SiO<sub>2</sub>/Si substrates before and after the sulfurization using the two-temperature-zone tube furnace. The color of the Mo thin film is fully changed after the sulfurization, indicating the formation of uniform MoS<sub>2</sub> layers regardless of the position. Fig. 1c displays an AFM image of synthesized MoS<sub>2</sub> layers, indicating that the root mean square (RMS) roughness of synthesized MoS<sub>2</sub> layers is 2.15 nm. The XPS spectra were acquired with a normal emission geometry using monochromatic Al K $\alpha$  radiation ( $h\nu = 1486.6$  eV) in an ultrahigh vacuum system (base pressure:  $\sim 10^{-9}$  Torr). The XPS survey, Mo 3d, and S 2p core level spectra of synthesized MoS<sub>2</sub> layers are displayed in Fig. 1d–f. The Mo, S, Si, O and C-related peaks are observed in the survey spectrum, which implies the presence of MoS<sub>2</sub> onto the SiO<sub>2</sub>/Si substrates. The Mo 3d and S 2p core level spectra of synthesized MoS<sub>2</sub> layers were deconvoluted by Gaussian-Lorentzian

fitting [18]. The Mo 3d core level spectrum obtained from the MoS<sub>2</sub> layers is shown in Fig. 1e. The Mo 3d<sub>5/2</sub> and 3d<sub>3/2</sub> peaks corresponding to MoS<sub>2</sub> appear at binding energies ( $E_B$ ) of 229.5 and 232.7 eV, respectively, and the S 2s peak emerges at  $E_B = 226.7$  eV. Fig. 1f shows that the S 2p<sub>3/2</sub> and S 2p<sub>1/2</sub> for MoS<sub>2</sub> are observed at  $E_B$  of 162.3 and 163.5 eV, respectively. The extracted atomic ratio of S and Mo is 1:1.9, suggesting that the synthesis of stoichiometric MoS<sub>2</sub> without the formation of Mo oxide was achieved. In general, the synthesis of large-scale MoS<sub>2</sub> layers has been demonstrated using pre-deposited Mo thin films by a sulfurization method, in which the formation of non-stoichiometric MoS<sub>2</sub> was inevitably induced by the diffusion limit of sulfur atoms. We carefully established the optimized conditions for complete sulfurization of the Mo films by precise control of the thickness of pre-deposited Mo films, sulfurization temperature, and time.

The layer homogeneity of synthesized MoS<sub>2</sub> was examined by confocal Raman mapping with an excitation wavelength of 532 nm for two typical Raman active modes including the A<sub>1g</sub> (out-of-plane vibration) mode and E<sub>2g</sub> (in-plane vibration) mode of MoS<sub>2</sub>, as seen in Fig. 2a and b. These results reveal excellent uniformity in terms of Raman frequency over large areas ( $50 \times 50 \mu\text{m}^2$ ), indicating successful synthesis of homogeneous MoS<sub>2</sub> layers, since the difference in two phonon modes provides the number of MoS<sub>2</sub> layers [19]. Fig. 2c displays a representative Raman spectrum with an excitation wavelength of 514 nm of synthesized MoS<sub>2</sub> on SiO<sub>2</sub>/Si. The E<sub>2g</sub> mode at  $380.5 \text{ cm}^{-1}$  and A<sub>1g</sub> mode at  $404.7 \text{ cm}^{-1}$  are observed. Based on the Raman results, the difference of A<sub>1g</sub> and E<sub>2g</sub> mode is  $24.2 \text{ cm}^{-1}$ , revealing that multilayer MoS<sub>2</sub> was synthesized. The optical transmittance of pre-deposited Mo thin films before and after sulfurization is shown in Fig. 2d. After sulfurization, the optical transmittance decreases from 86.11 to 69.84% at 550 nm in

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